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Influence of SF₆ on HF Laser Plasma Parameters (*).

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Summary. - This paper presents the results of calculations of electron drift velocity, mean energy and ionization, and attachment coefficients in SF6: C3H8: He mixtures performed according to the multiterm Boltzmann-equation analysis. The parameters for wide variation of gas mixture composition and E/N values are obtained. The results presented may be useful in studying the HF laser action, analysis of the gas discharge, and research, development and modelling of this type of lasers.

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1. - Introduction.

Gas mixtures $SF_6: C_3H_8:$ He are of great interest now due to their usage in HF chemical lasers-high-power radiation sources in 2.5-3.5 µm range having a large number of recent applications [1-6].

The vibrationally excited HF* molecules responsible for HF laser operation are produced by the following reactions in an electric discharge:

$$SF_6 + e \rightarrow SF_5 + F + e^-$$
.

$$F + C_3 H_8 \rightarrow C_3 H_7 + HF^*$$
.

That is the reason of investigating mixtures containing SF₆, C₃H₈ and He, and the influence of SF₆ on plasma parameters. The results presented for these mixtures are probably the first to be published in literature.

^(*) The authors of this paper have agreed to not receive the proofs for correction.

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2. - Cross-sections.

The mixtures under consideration contain three kinds of gases— SF_6 , $\mathrm{C}_3\mathrm{H}_8$ and He. In order to obtain plasma parameters, the cross-section data for the elementary processes with electrons should be available.

The SF₆ molecule has «sophisticated» shapes of electron collision cross-sections

The elastic momentum transfer cross-section is 2.7·10⁻¹³ cm² at an electron energy of $0\,\text{eV}$ and decreases to $8\cdot 10^{-16}\,\,\text{cm}^2$ at $1\,\text{eV}.$ Then it increases to $17.6 \cdot 10^{-16}$ cm² for an energy of $7.6 \, \mathrm{eV}$, it changes slightly remaining of order $16\cdot 10^{-16}~{
m V\cdot cm^2}$ in the range 8-25 eV and tends to decrease monotonically to 0 for an electron energy of 1000 eV.

The cross-section for the inelastic process of attachment has the most specific behaviour. It has a value of $3 \cdot 10^{-13}$ cm² at $0 \, \text{eV}$ which decreases to a magnitude of order $10^{-14}~\mathrm{cm^2}$ at $0.08~\mathrm{eV}$. In $0.1\text{--}3~\mathrm{eV}$ region a rapid fall to 0 is observed. Beyond this point the cross-section has values of order $10^{-18}~{\rm V\cdot cm^2}$ and it is 0 at an electron

The vibrational excitation with a threshold of 0.096 eV has values of cross-section energy of 16 eV. larger than the elastic momentum transfer one in the 0.5-2.5 eV range. The other processes for the SF₆ molecules taken into account are vibrational excitation

(0.065 eV), electronic excitation (9.8; 13.3 eV) and ionization (15.7 eV).

The elastic momentum transfer cross-section for $\mathrm{C}_3\,\mathrm{H}_8$ molecules has a minimum occurring at an energy 0.11 eV but it remains higher than the cross-sections of the inelastic processes in the energy region 0.001-1000 eV. The inelastic processes included in our calculations are as follows: vibrational excitation (0.093 eV; 0.358 eV), electronic excitation (6.8 eV; 9.1 eV), ionization (11.14 eV), attachment (6 eV).

Helium is a well-known gas and we will not discuss here the behaviour of its

collision cross-section.

All cross-section data used in the present investigation are from [7,8].

The peculiarity of the cross-sections set for SF₆, especially the high intensity of the inelastic collision processes, requires multiterm Boltzmann-equation analysis for plasma characteristics calculation. The results presented are obtained by Galerkin's method using B-splines as basis functions. This technique was offered by Pitchford et al. [9] and it has been used by many authors.

3. - Results.

E/N values for which the calculations have been made are in a wide region and correspond to the values used in a real HF laser[6].

3.1. Ionization and attachment rate coefficients. - Calculated values of the ionization and attachment rate coefficients, K_i and K_a , for three different mixtures are shown in fig. 1 and 2. Also, K_i and K_a values calculated for $E/N = 1 \cdot 10^{-15} \text{ V} \cdot \text{cm}^2$ are plotted in fig. 3 as a function of ${\rm SF}_6$ flow rate.

An increasing of SF₆ quantity in the mixture decreases the ionization coefficient

due to the strong electronegativity of SF6 molecules.

Using the results for K_i and K_a the effective ionization coefficient $(K_i - K_a)$ and the limiting field to gas number density ratio $(E/N)^*$ at which $K_{\rm i}-K_{\rm a}=0$ can be

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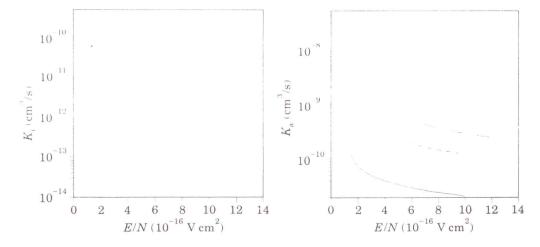


Fig. 1. Fig. 2.

Fig. 1. – The ionization rate coefficient K_i vs. the reduced electric field E/N for mixtures $SF_6: C_3H_8: He = 0.2: 0.07: 7 1/min (---), 1: 0.07: 7 1/min (---), 2: 0.07: 7 1/min (---).$

Fig. 2. – The attachment rate coefficient K_a vs. the reduced electric field E/N for mixtures $SF_6: C_3H_8: He = 0.2: 0.07: 7 l/min (---), 1: 0.07: 7 l/min (---), 2: 0.07: 7 l/min (---)$

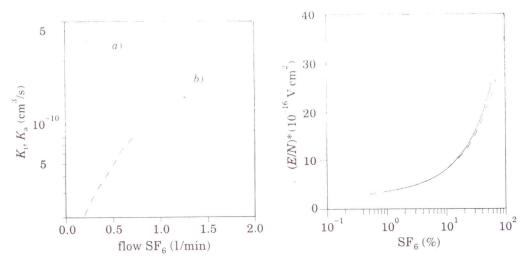


Fig. 3. Fig. 4.

Fig. 3. – The ionization (a)) and attachment (b)) rate coefficients as a function of SF₆ flow rate at $E/N = 1 \cdot 10^{-15} \text{ V} \cdot \text{cm}^2$.

Fig. 4. – The limiting reduced field $(E/N)^*$ vs. the SF₆ concentration for mixtures SF₆: He: — present calculation, – – – Kleine et al. [10].

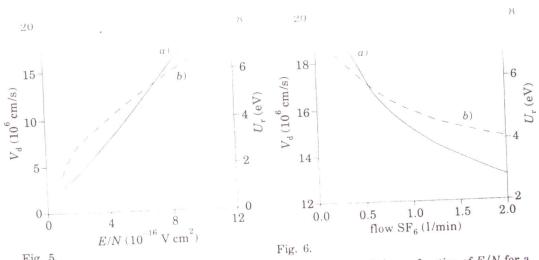


Fig. 5. – The electron drift velocity $V_{\rm d}$ (a) and mean energy $U_{\rm r}$ (b) as a function of E/N for a mixture flow rate $SF_6: C_3H_8: He=0.2:0.07:7$ 1/min.

Fig. 6. – The electron drift velocity $V_{\rm d}\left(a\right)$) and mean energy $U_{\rm r}\left(b\right)$) as a function of SF $_{\rm f}$ flow rate at $E/N = 1 \cdot 10^{-15} \text{ V} \cdot \text{cm}^2$.

obtained. This quantity is needed to predict the breakdown field and the operating

field in a self-sustained glow discharge. In fig. 4 the calculated values of $(E/N)^*$ for mixtures ${
m SF}_6$: He as a function of ${
m SF}_6$ concentration in comparison with those given in [10] are presented. The agreement with the values calculated in [10] proves to be very good.

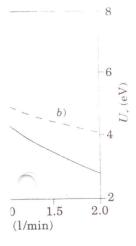
3.2. Electron drift velocity $V_{\rm d}$ and mean energy $U_{\rm r}.$ - Figures 5 and 6 show the electron drift velocity $V_{\rm d}$ (curve a)) and mean energy $U_{\rm r}$ (curve b)) as a function of the reduced electric field E/N for the flow ratio of the ${
m SF}_6:{
m C}_3{
m H}_8:{
m He}$ mixture $0.2:0.07:71/\min$ at an overall atmospheric pressure and SF₆ flow rate for E/N=

The electron drift velocity $V_{
m d}$ increases with the reduced electric-field E/N= $1 \cdot 10^{-15} \text{ V} \cdot \text{cm}^2$, respectively. growth (fig. 5, curve a)) which corresponds to the higher electrical power stored in the discharge. An adding of SF6 molecules in the mixture leads to a drift velocity decrease (fig. 6, curve a)). The reason is the much larger momentum transfer collision cross-section for ${\rm SF}_6$ than the respective one for He and ${\rm C}_3\,{\rm H}_8$ molecules.

At low E/N values the mean energy increases faster than at high values (fig. 5, curve b)). The more the SF_6 molecules in the mixture, the lower the mean energy (fig. 6, curve b)) because the fraction of He molecules decreases. At high concentration of He the mean energy is higher as the electrons have smaller losses for vibrational levels excitation.

4. - Conclusion.

The results obtained demonstrate a strong influence of the SF₆ molecules quantity in the gas mixture upon the electron drift velocity, the mean energy, and ionization



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and attachment rate coefficients. Thus ${\rm SF_6}$ molecules play an important role in the discharge plasma. These results may be useful for HF laser development and modelling.

In a real HF laser plasma some of the components disintegrate and HF molecules are formed. The decreasing of SF_6 and C_3H_8 molecules' concentration in the mixture is not taken into account in the present calculation. Data for the formed HF molecules' number may be obtained in case of a given laser system by using the output laser characteristics and the number of generated photons. This problem will be considered in a future work.

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